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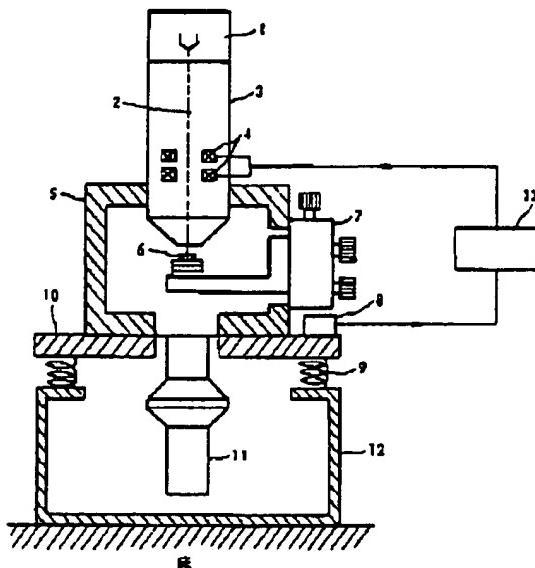
APPLICATION DATE : 26-11-92
APPLICATION NUMBER : 04316781

APPLICANT : HITACHI LTD;

INVENTOR : OTAKA TADASHI;

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TITLE : SCANNING ELECTRON MICROSCOPE



ABSTRACT : PURPOSE: To provide a scanning electron microscope which is prevented from generating relative displacement between an electron beam and a sample due to the vibration of the ground and the like.

CONSTITUTION: This device has a vibration detector 8 and a control circuit 13 for deflecting an electron beam 2 with a deflection coil 4 in accordance with a signal from the vibration detector 8. The vibration which causes relative displacement between the electron beam 2 and a sample is detected by the vibration detector 8, and the control circuit 13 brings a current into the deflection coil 4 by using the detection signal of the vibration detector 8 to deflect the electron beam 2 so as to reduce relative displacement between the electron beam 2 and the sample. Thereby, the relative displacement caused by vibration can be corrected by deflecting an electron beam, so that the secondary electron image disturbance caused by the vibration of the ground at every possible frequency and amplitude, and also by the vibration of acoustic waves may be prevented.

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